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Docket No.: SON-1745 (PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Seiichi FUKUDA

Confirmation No.: 5387

Application No.: 09/512,336 ✓

Art Unit: 1765

Filed: February 24, 2000

Examiner: K. Chen

For: DRY ETCHING METHOD AND METHOD
OF MANUFACTURING SEMICONDUCTOR
APPARATUS

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TC 1700

TRANSMITTAL OF APPEAL BRIEF

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Three copies of an Appellant's Brief on Appeal for the above-referenced application are being filed herewith. The Commissioner is hereby authorized to charge \$330.00 to Deposit Account 18-0013 to cover the requisite fee under 37 C.F.R. 1.16 or 1.17 which may be required, or to credit any overpayment.


The Notice of Appeal for this application was filed on August 22, 2003.

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Consideration of the Appeal Brief is respectfully requested.

Respectfully submitted,

DATE: October 21, 2003



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